



# First Commissioning Results of An Evaporative Cooling Magnet ECRIS-LECR4

**W. Lu, L. T. Sun, X. Z. Zhang, Y. C. Feng, C. Qian, Y. Cao,  
H. Y. Ma, Y. Yang, P. Y. Liu, B. H. Ma and H. W. Zhao**

**Institute of Modern Physics (IMP), CAS  
Lanzhou, 730000, China**

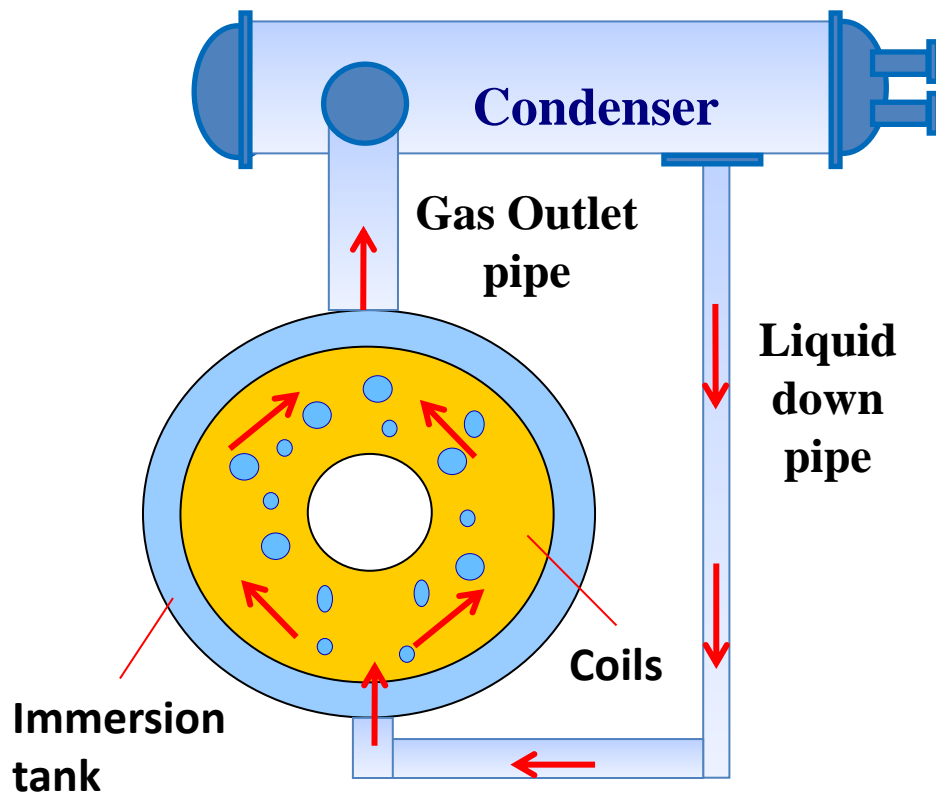
*E-mail address: luwang@impcas.ac.cn*



# Evaporative Cooling Technology

Evaporative cooling technology (Developed by Institute of Electrical Engineering, Chinese Academy of Sciences- IEE, CAS):

It is based on the principle of phase change heat transfer; High insulating and room-temperature boiling point organic coolant is used to absorb the heat of electrical equipment.



Is it possible to use this technology in an ECR ion source magnet?



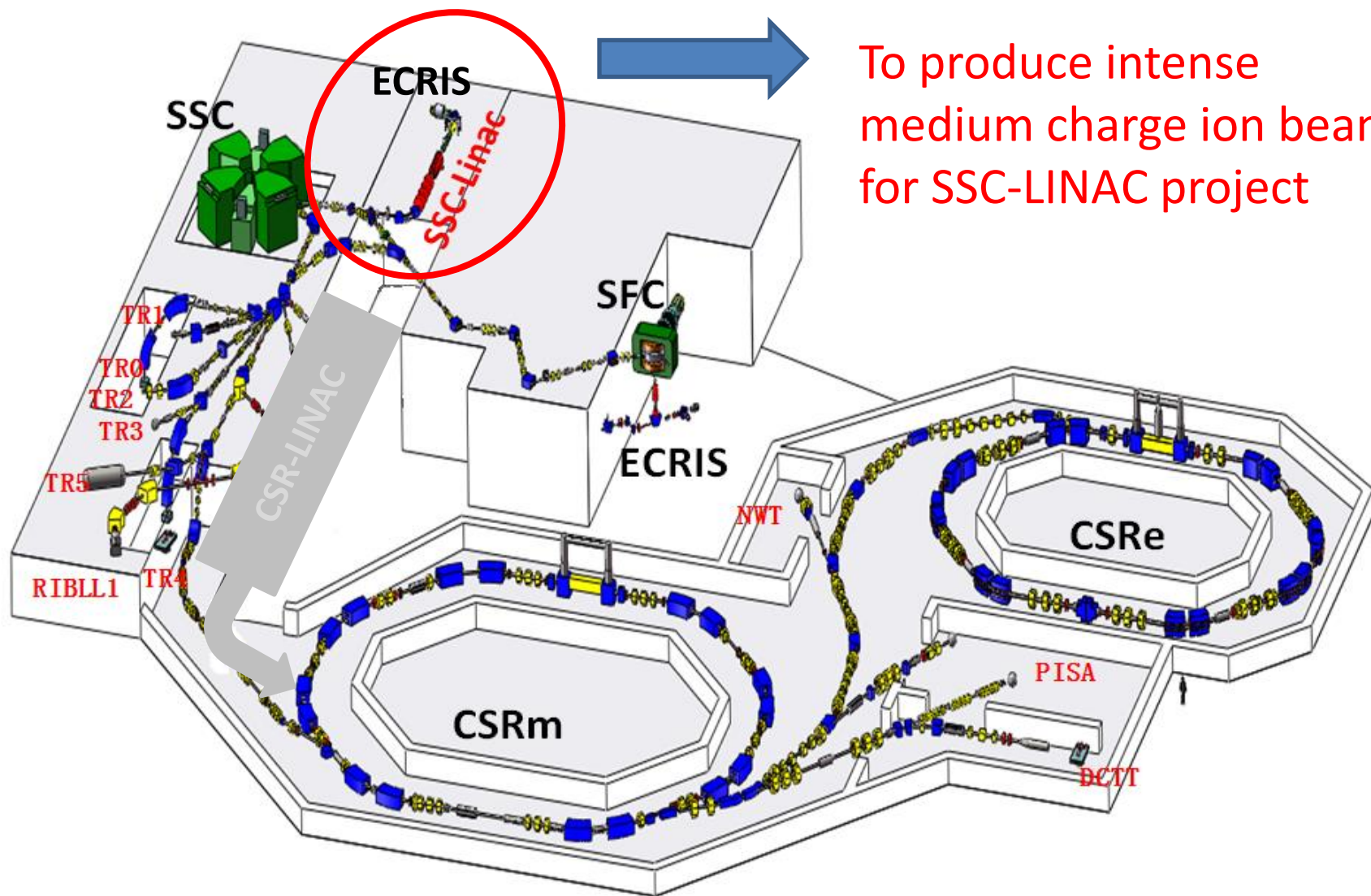
# OUTLINE

LECR4 (Former name DRAGON): Lanzhou ECR ion source No. 4

- Motivation of LECR4 ECR ion source
- LECR4 Structure & Features
- Preliminary Commissioning results
- Summary



# HIRFL Layout

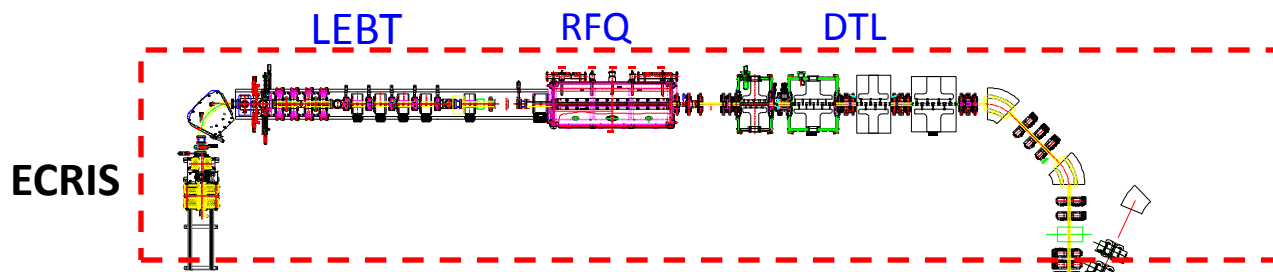


To produce intense medium charge ion beams for SSC-LINAC project

**SSC-LINAC project: A new heavy ion injector for SSC cyclotron at IMP, Lanzhou**

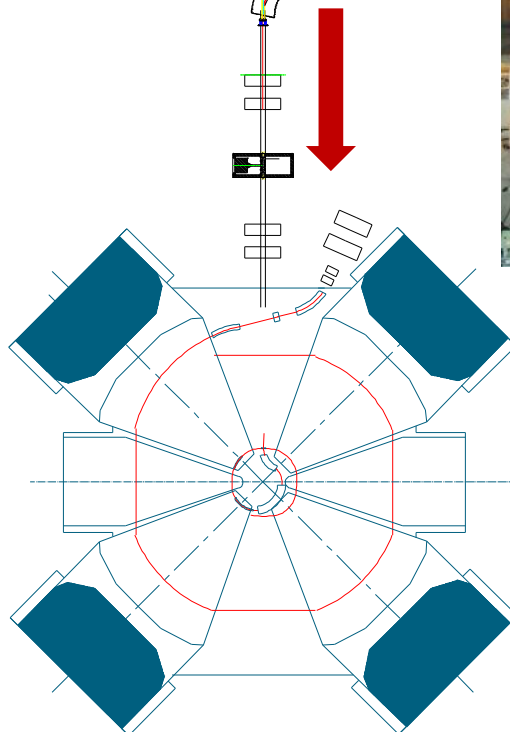


# SSC-LINAC layout



## SSC-LINAC:

- ◆ Ion Species: C-U, CW ion beam
- ◆ Input Energy: 3.728 keV/u
- ◆ Beam emittance:  $<150 \pi \cdot \text{mm} \cdot \text{mrad}$



## SSC

K=450 –100AMev

Injection Energy:

1 Mev/u-10 Mev/u

**An ECRIS can meet the demand, include RT ECRIS, SC ECRIS, etc...**



# What type of ECRIS we need?

**Lower cost and easy maintenance**



**Room temperature ECRIS**

**Higher current density & axial magnetic field**

(Compared with LECR3, another RT ECRIS at IMP)



**Evaporative cooling technology**

**Intense medium charge state ion beams**



**Rf frequency: 18 GHz.**

*Can produce  $O^{6+}$ ,  $Ar^{9+}$ ,  $Xe^{20+}$ ,  $Bi^{28+}$ , etc...*

**LECR4 is a RT ECRIS with Evaporative cooling technology. (cooperated with IEE, CAS)**





# Magnetic Field Design

## Parameters of SECRAL

|                                  | SECRAL<br>18 GHz                                       | SECRAL<br>24 GHz |
|----------------------------------|--|------------------|
| Operating<br>Frequency (GHz)     | 18   | 24               |
| Resonance<br>Length (mm)         | 105  | 110-120          |
| Plasma Chamber<br>(mm)           | Length: 420<br>Diameter: 126<br>Effective volume: ~5 L |                  |
| Axial Injection<br>field (T)     | 2.5  | 3.7              |
| Axial Extraction<br>field (T)    | 1.4  | 2.2              |
| Max. Chamber<br>Radial field (T) | 1.4  | 2.0              |

## SECRAL, 18-24 GHz, IMP



## Performance of SECRAL at 18 GHz

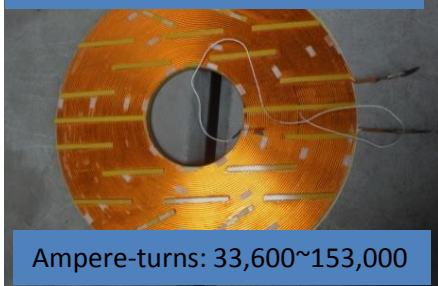
|                   |                 | SECRAL |
|-------------------|-----------------|--------|
| $f$ (GHz)         |                 | 18     |
| $^{16}\text{O}$   | 6 <sup>+</sup>  | 2300   |
|                   | 7 <sup>+</sup>  | 810    |
| $^{40}\text{Ar}$  | 11 <sup>+</sup> | 810    |
|                   | 12 <sup>+</sup> | 510    |
| $^{129}\text{Xe}$ | 20 <sup>+</sup> | 505    |
|                   | 27 <sup>+</sup> | 306    |
| $^{209}\text{Bi}$ | 30 <sup>+</sup> | 101    |
|                   | 28 <sup>+</sup> | 214    |
|                   | 30 <sup>+</sup> | 191    |

# Magnet Structure of LECR4

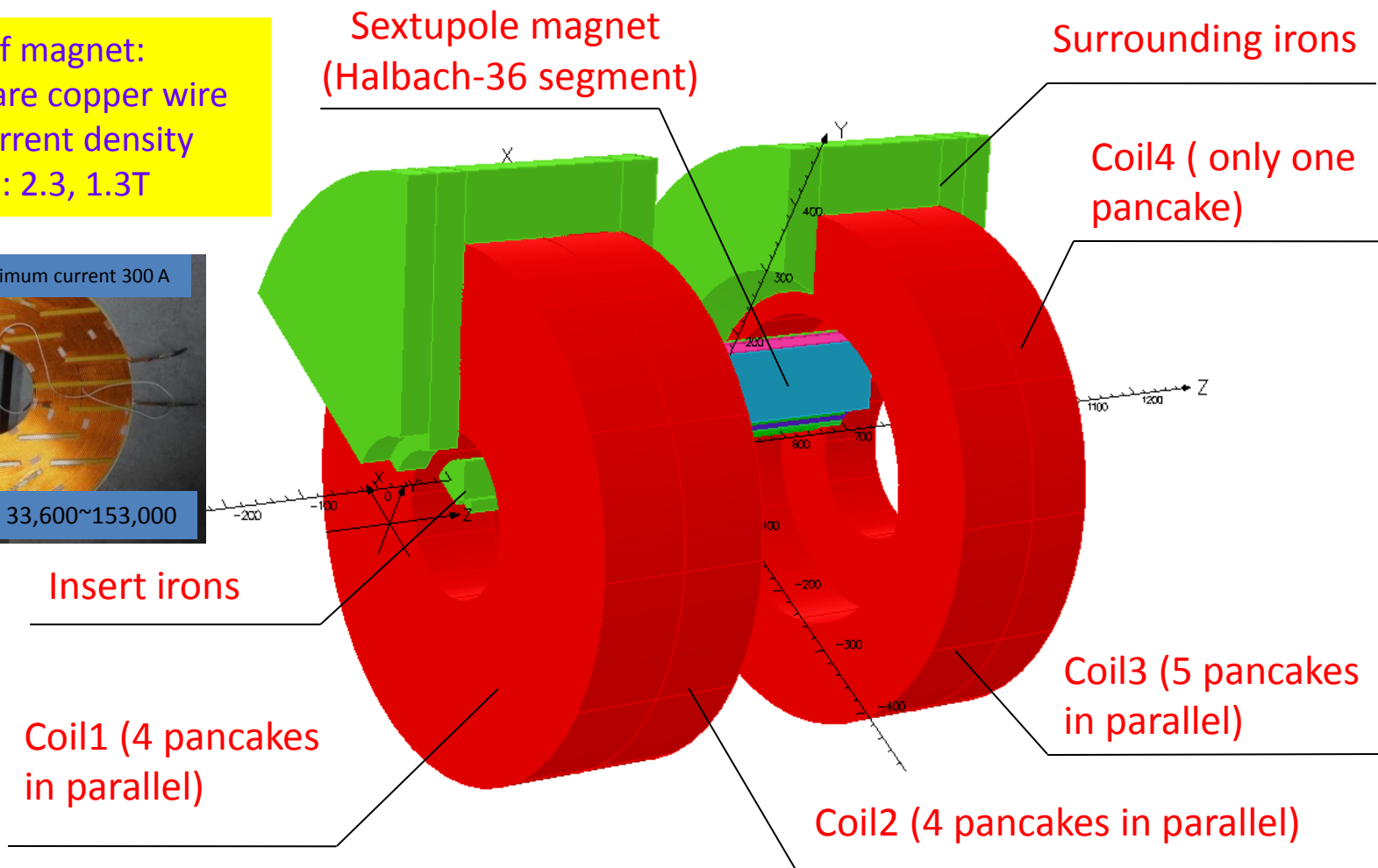
Features of magnet:

- Solid square copper wire
- Higher current density
- Axial field: 2.3, 1.3T

One pancake: Maximum current 300 A



Ampere-turns: 33,600~153,000



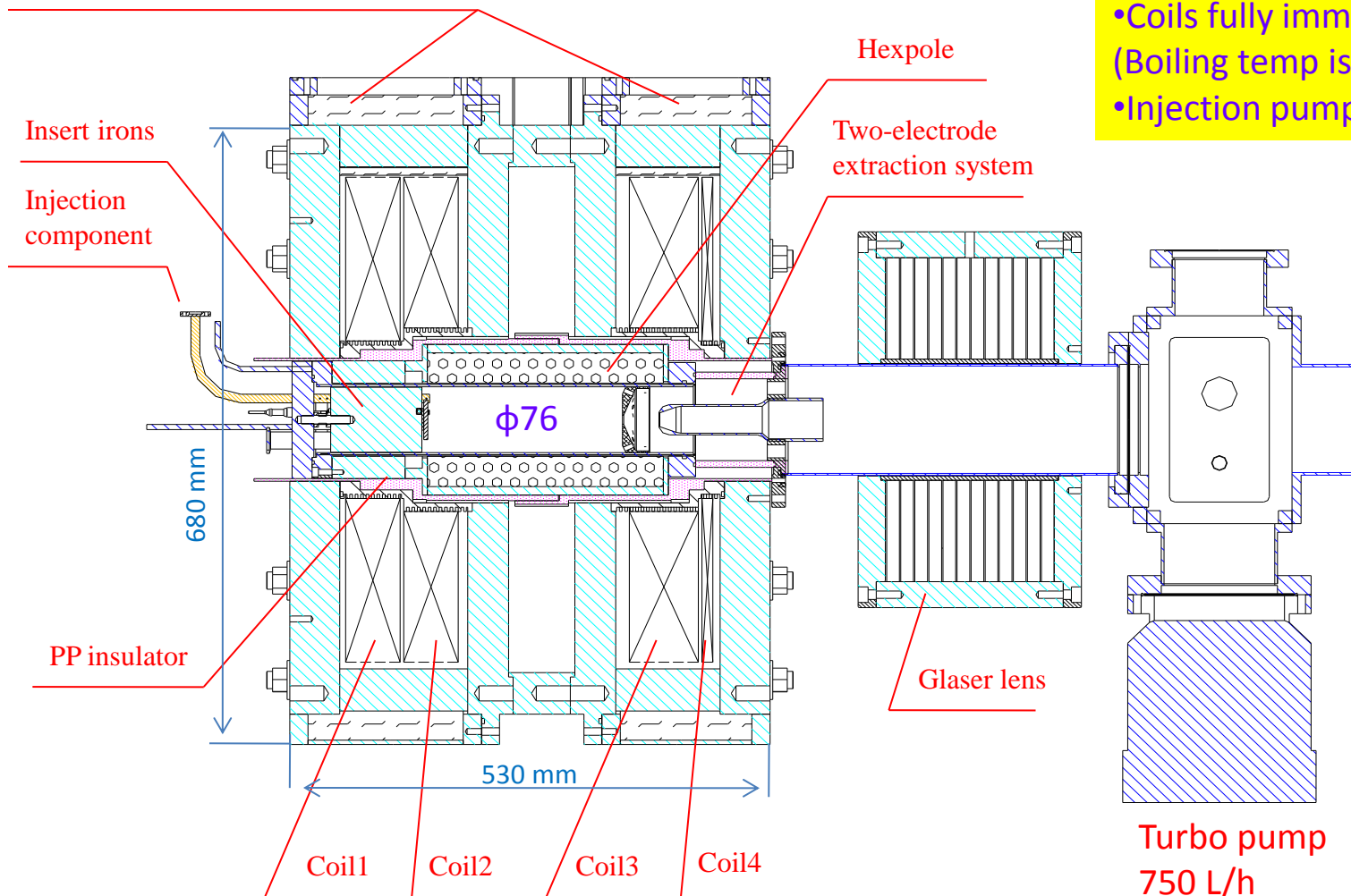
**Current density: 11.85 A/mm<sup>2</sup> (slightly higher than LECR3)**

Maximum exciting current of Coil1, 2, 3 and 4: 1200 A, 1200 A, 1500 A and 300 A



# Schematic View of LECR4

Coolant (Boiling Temperature: 47.7 °C)

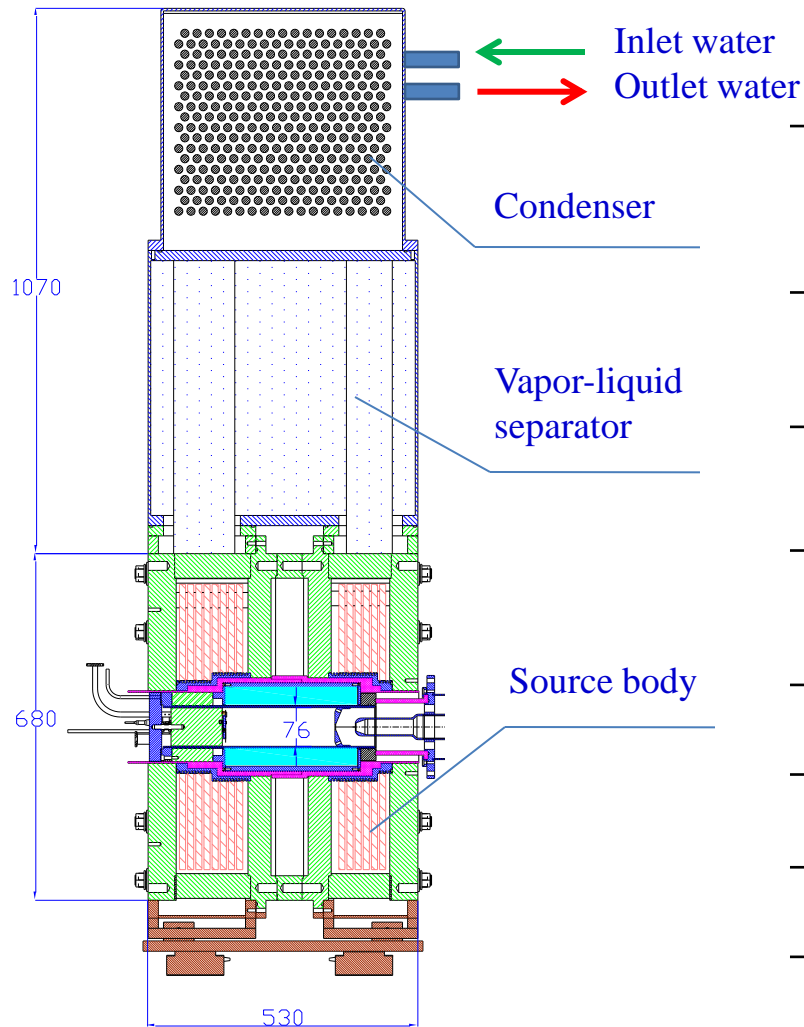


Features:

- Coils fully immersed in coolant (Boiling temp is 47.7 °C)
- Injection pump free



# Designed Parameters



Parameters of LECR4

|                               | LECR4            | LECR3            | SECRAL<br>18 GHz  |
|-------------------------------|------------------|------------------|-------------------|
| Operating Frequency (GHz)     | 18               | 14.5             | 18                |
| Resonance Length (mm)         | 18GHz:<br>118    | 14.5GHz:<br>86   | 105               |
| Plasma Chamber (mm)           | L: 220<br>ID: 76 | L: 220<br>ID: 76 | L: 420<br>ID: 126 |
| Axial Injection field (T)     | 2.3              | 1.7              | 2.5               |
| Axial Extraction field (T)    | 1.3              | 1.1              | 1.4               |
| Max. Chamber Radial field (T) | 1.0- 1.1         | 1.0-1.1          | 1.4               |
| Total Power (kW)              | 195              | 100              | -                 |

**Weight: ~1.5 Tons**



DC-BREAK

WR62 waveguide

Injection component



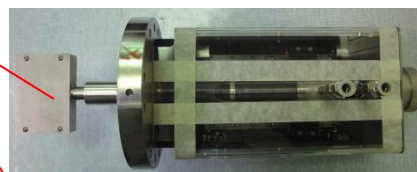
Insulator and Hexpole



Allison Scanner



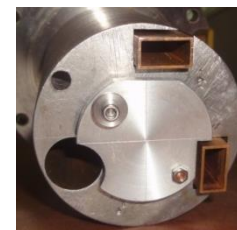
X & Y Slits



Faraday cup



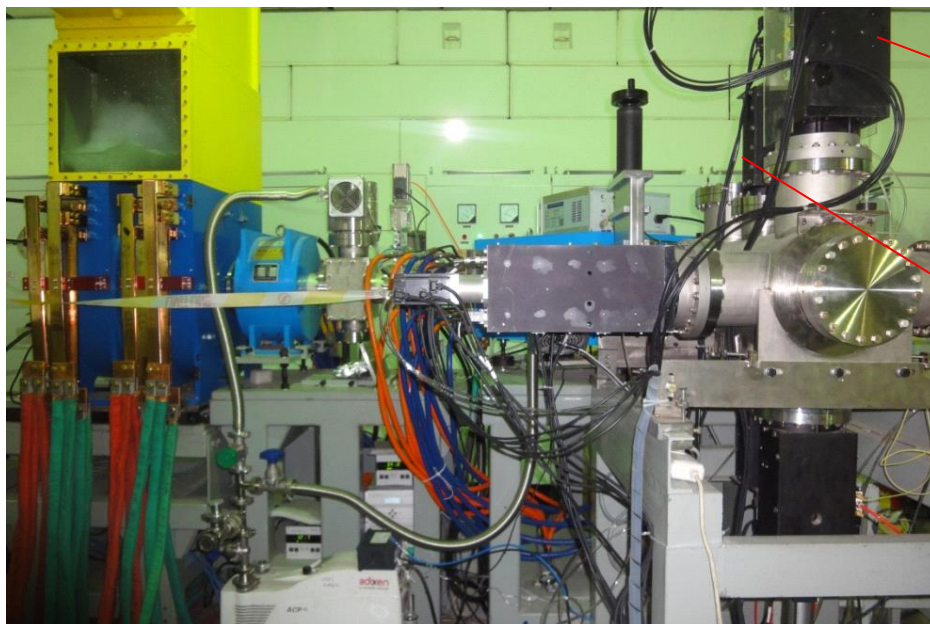
Biased disk



SS plasma chamber



Pin valves



**In July 2013**



# First Magnet Test after Assembly at IMP





# First Magnet Test after Assembly at IMP



**Current =0**

# First Magnet Test after Assembly at IMP



Current =0

30% Current



# First Magnet Test after Assembly at IMP



Current =0

30% Current

100% Current

# First Magnet Test after Assembly at IMP



**Current =0**

**30% Current**

**100% Current**

**Temperature**

Safety operation requirements:  $T_{\text{Coil}} < 120 \text{ }^{\circ}\text{C}$ ;  $T_{\text{warm-bore}} < 80 \text{ }^{\circ}\text{C}$ .



# First Magnet Test after Assembly at IMP



Current =0

30% Current

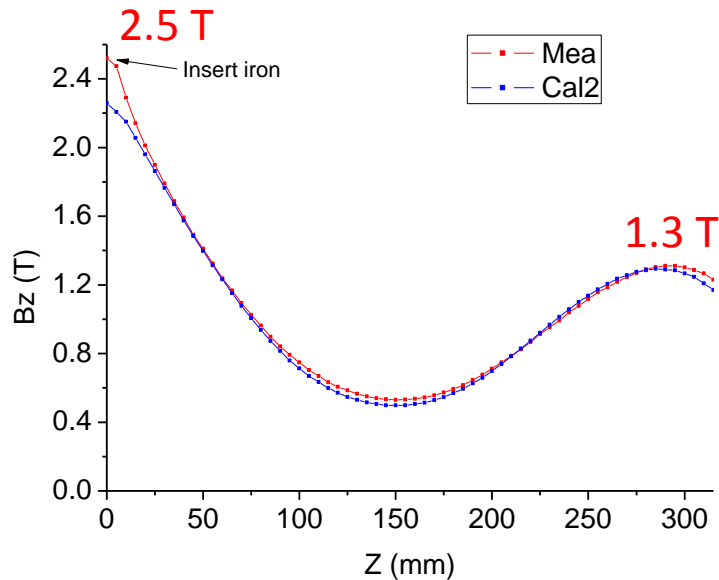
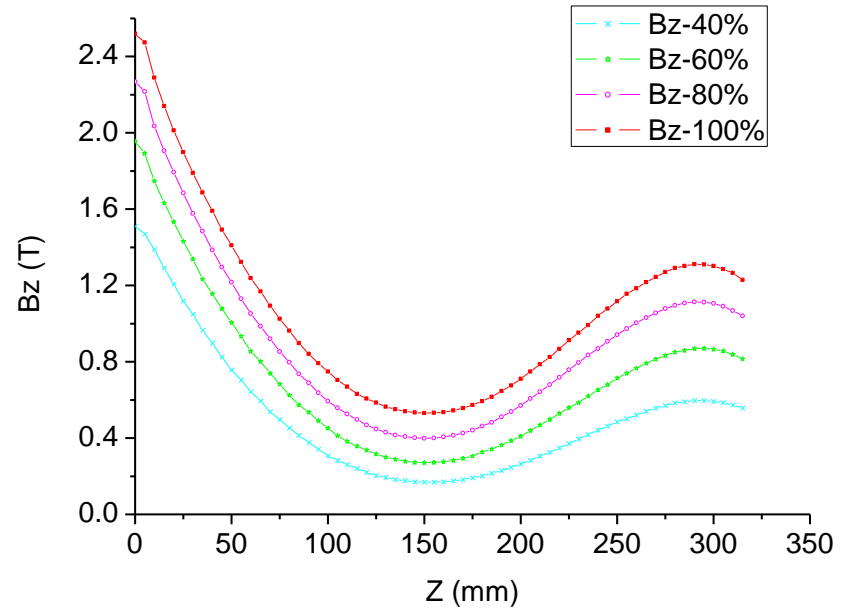
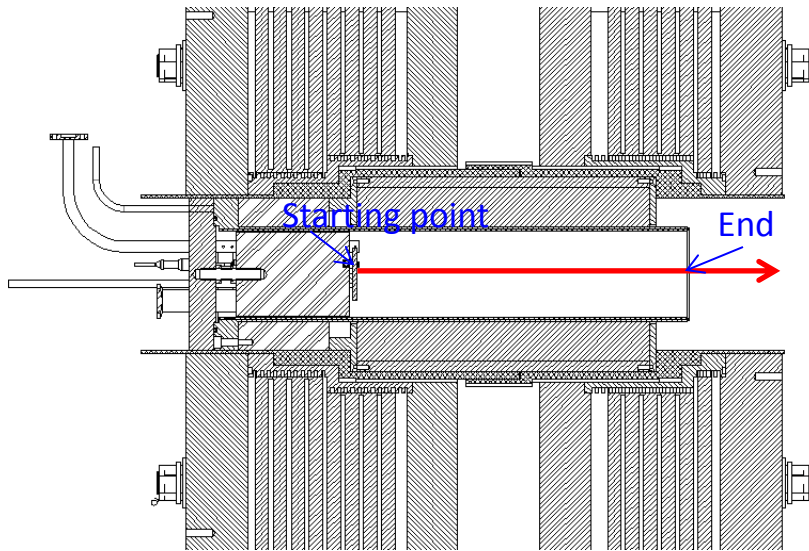
100% Current

Temperature

Safety operation requirements:  $T_{\text{coil}} < 120 \text{ }^{\circ}\text{C}$ ;  $T_{\text{warm-bore}} < 80 \text{ }^{\circ}\text{C}$ .



# Axial Field Mapping



**The measured field distribution agrees well with the calculated result!**



# Unique Features of LECR4 ECR ion source



## LECR4— Room Temperature ECR Ion Source with New Coil Cooling Technique !

- ✓ Axial solenoids cooled with evaporative cooling medium
  - Higher axial magnetic field is possible
  - High-pressure de-ionized water free
- ✓ Injection pump free
  - Very simple injection part: easy maintenance and installation
  - More compact and lower cost
- Disadvantage:
  - Big magnet size





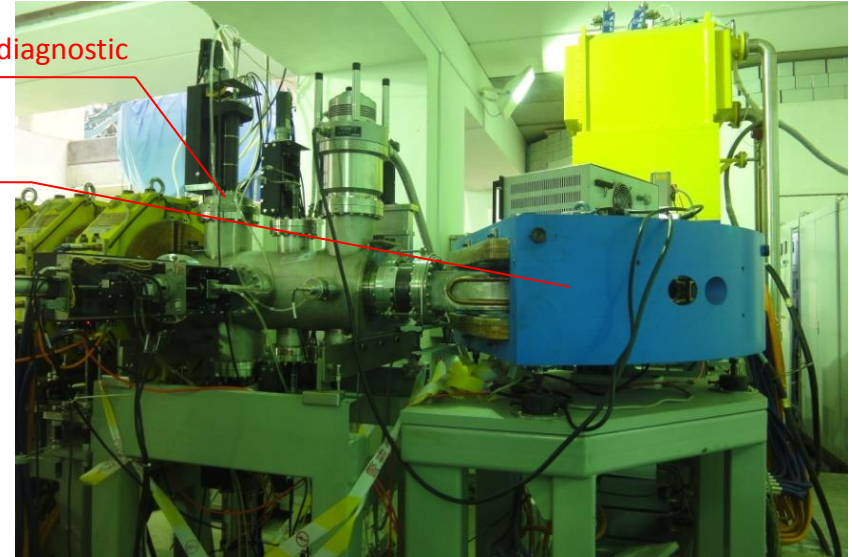
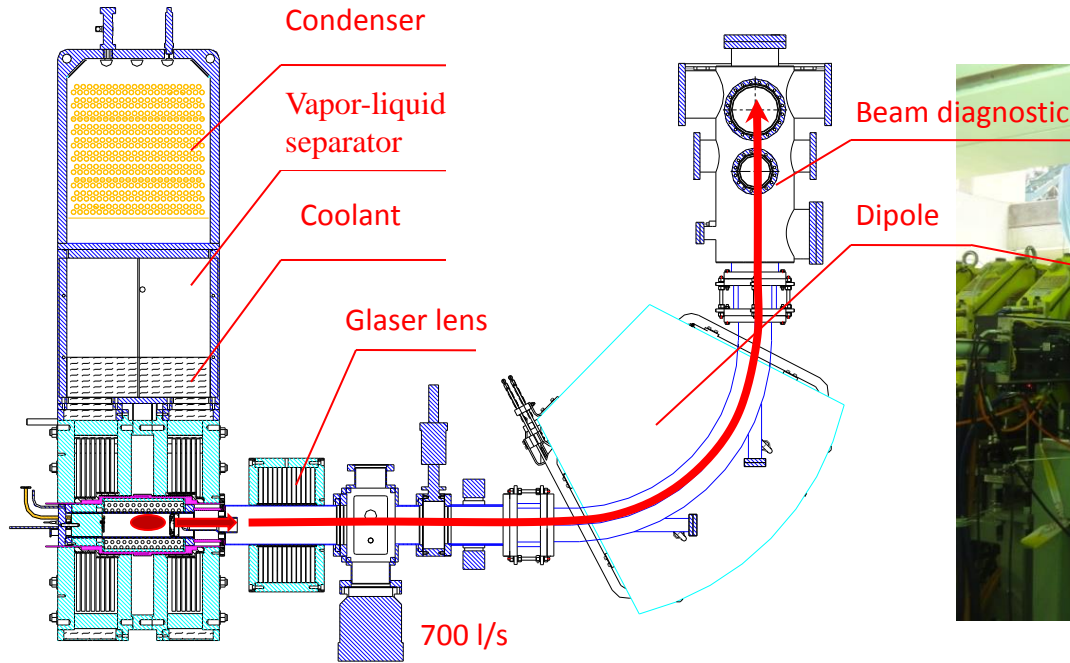
# LECR4 Milestone and Status



- 01. 2010 – **Project approved.**
- 07. 2010 – Preliminary concept design finished, called DRAGON
- 10. 2010 – DRAGON Coil1 prototype reached current 280A, but local temperature in the coils exceed 150 degree.
- 08. 2011 – DRAGON Coil1+Coil2 prototype reached current 100% (300A), maximum temperature in the coils is 83 degree.
- 09. 2012 – Final concept design finished, called **LECR4**
- 07. 2013 – **LECR4 overall assembly at IMP**
- 10. 2013 – Axial magnetic field reached 100% of its design field.
- 02. 2014 – **LECR4 First Analyzed Beam at 18 GHz.**
- 03. 2014-06.2006 — LECR4 Commissioning for intense highly charged beam
- 03. 2014 & 05. 2014 — One week's RFQ experiment using LECR4 beam



# Beam Transport Line



## Main Design Issues:

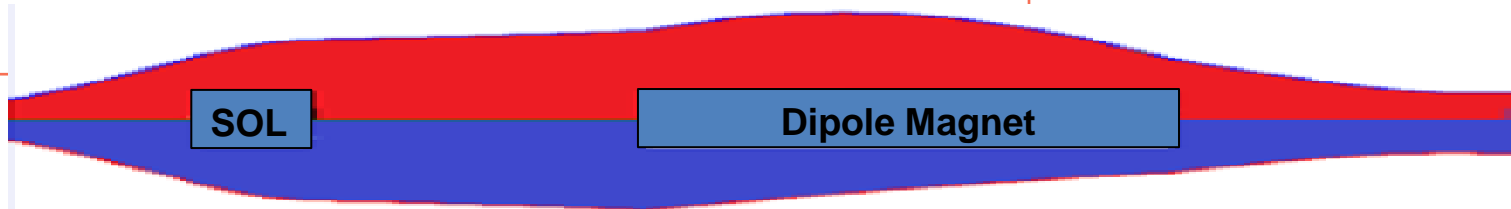
1. Solenoid close to the source body
2. Large acceptance dipole magnet & high transmission efficiency

Dipole magnet:

Bending angle: 90 degree

Bending radius: 600 mm

Pole gap: 130 mm



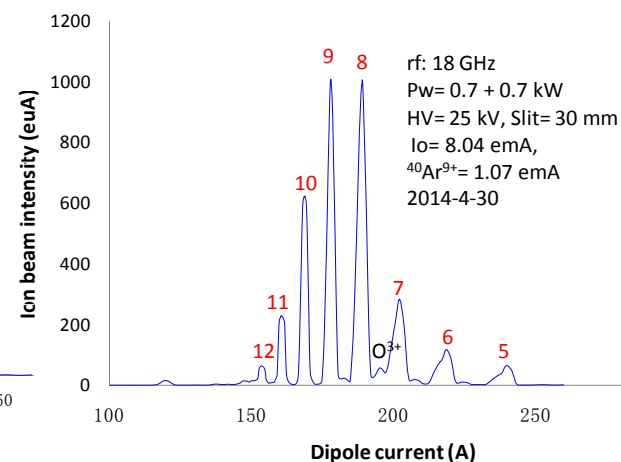
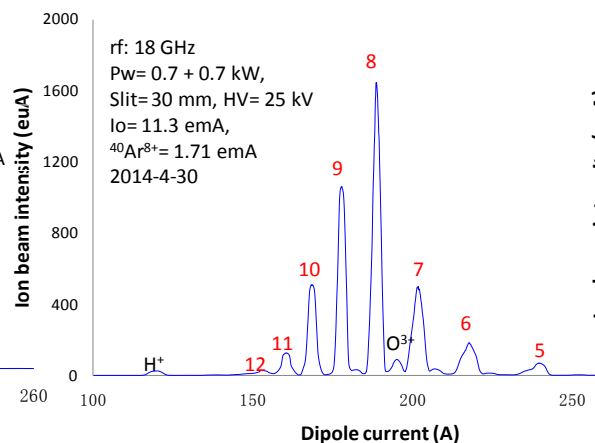
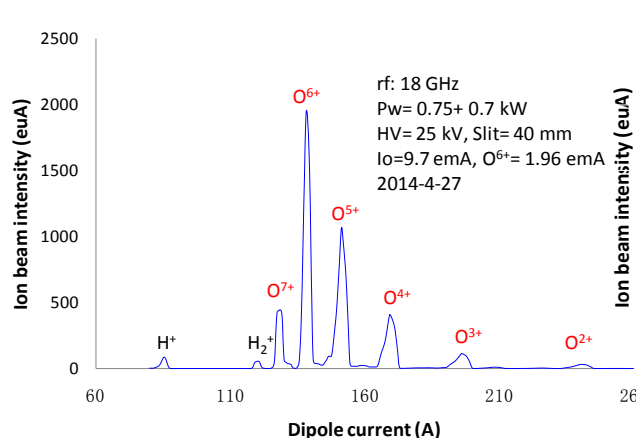


# LECR4 Tuning Conditions

- Plasma Chamber:       Stainless steel, ID:  $\varnothing 76$  mm
- RF Frequency:                               18 GHz
- Maximum RF Power:                       1.6 kW
- Extraction High Voltage:               15~25 kV
- Plasma Electrode Aperture:            $\Phi 10$  mm
- Puller Electrode Aperture:            $\Phi 16$  mm
- FC Negative Biased Voltage:       -150 V
- X-Slits:                                       16 mm~40 mm
- Ion Species:           Oxygen, Argon, Xenon, Bismuth



# Gaseous Ion Beams Production

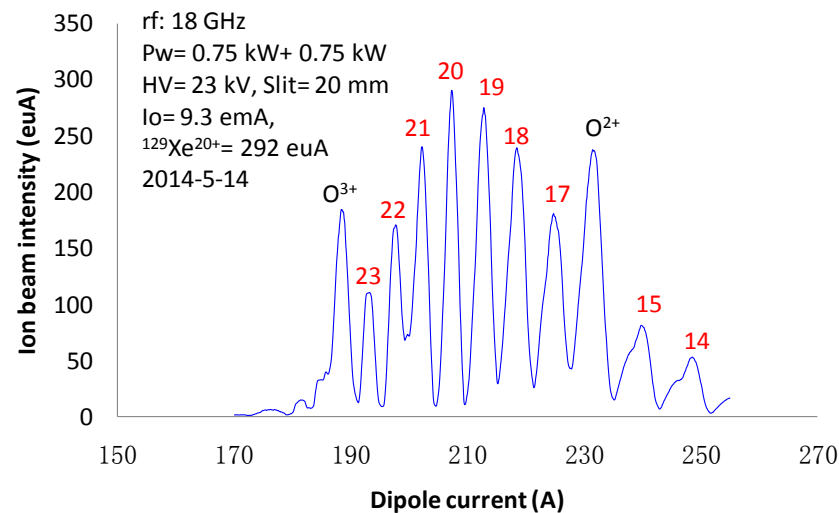


$O^{6+}$ : 1960 eμA (1.45 kW, 25 kV)  
 $B_r$  1.0 T,  $B_{inj}$  2.5 T,  $B_{ext}$  1.01 T,  $B_{min}$  0.45 T

$Ar^{8+}$ : 1710 eμA (1.40 kW, 25 kV)  
 $B_r$  1.0 T,  $B_{inj}$  2.5 T,  $B_{ext}$  0.9 T,  $B_{min}$  0.4 T

$Ar^{9+}$ : 1070 eμA (1.40 kW, 25 kV)  
 $B_r$  1.0 T,  $B_{inj}$  2.5 T,  $B_{ext}$  0.95 T,  $B_{min}$  0.4 T

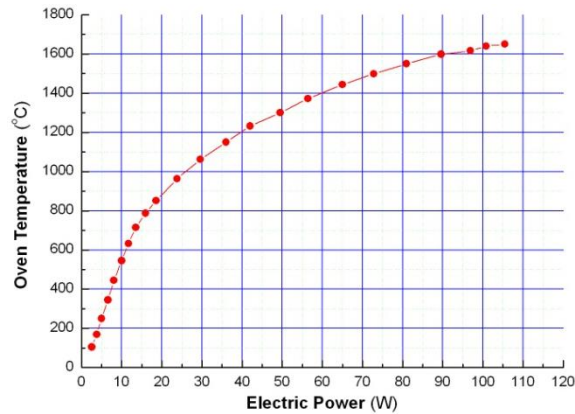
$Xe^{20+}$ : 292 eμA (1.50 kW, 25 kV)  
 $B_r$  1.0 T,  $B_{inj}$  2.5 T,  $B_{ext}$  1.0 T,  $B_{min}$  0.43 T



# Preliminary Test of Metallic Beam



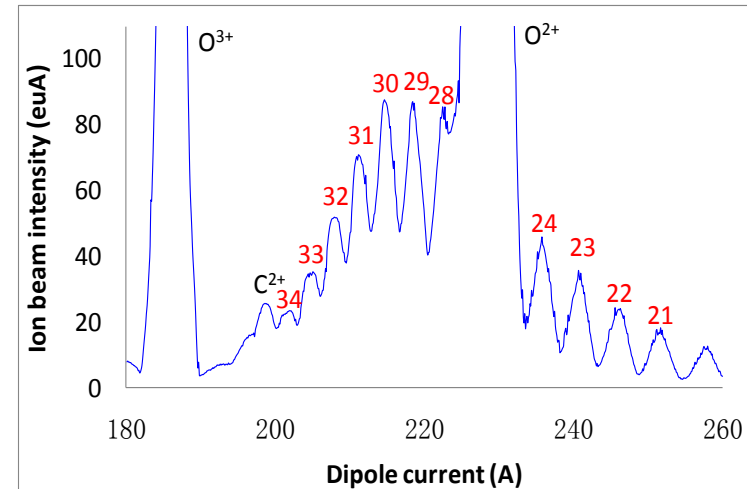
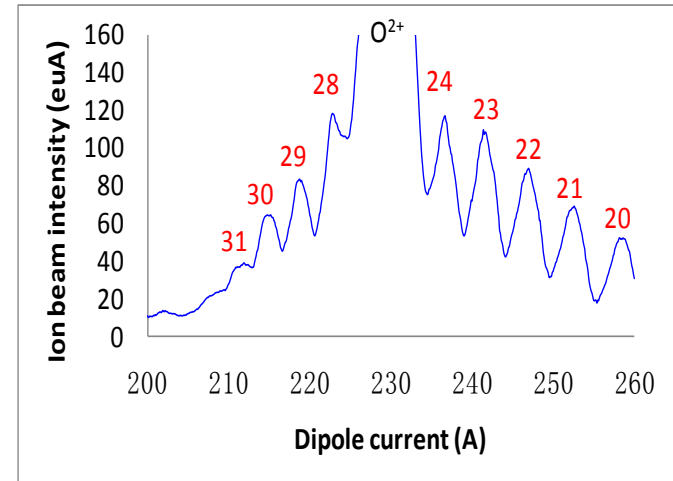
Micro-oven



With maximum  $P_{rf}=1.6$  kW, some preliminary but very promising metallic ion beams were produced:

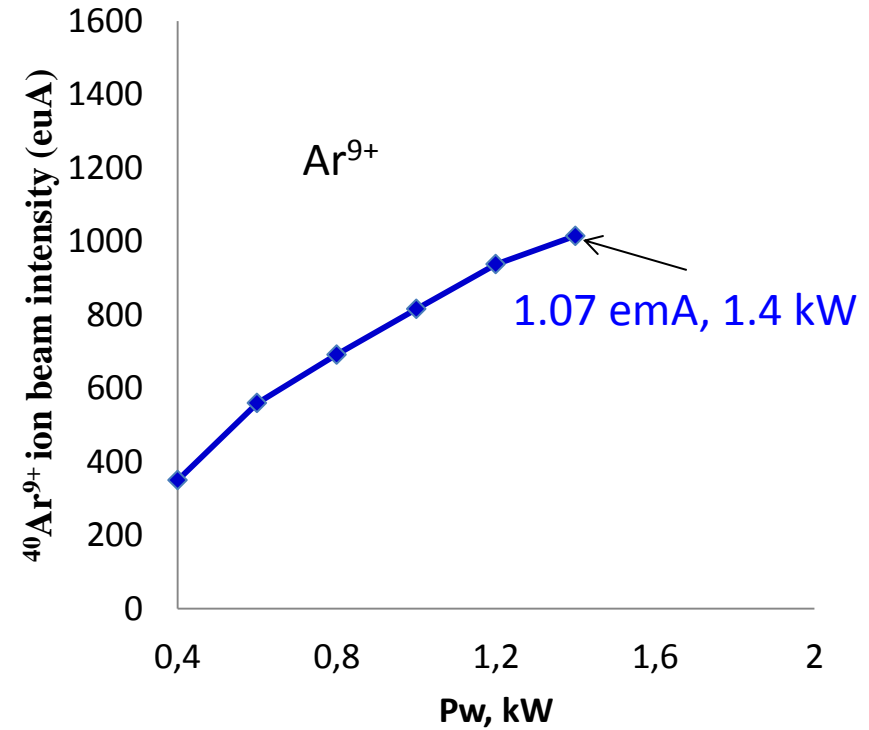
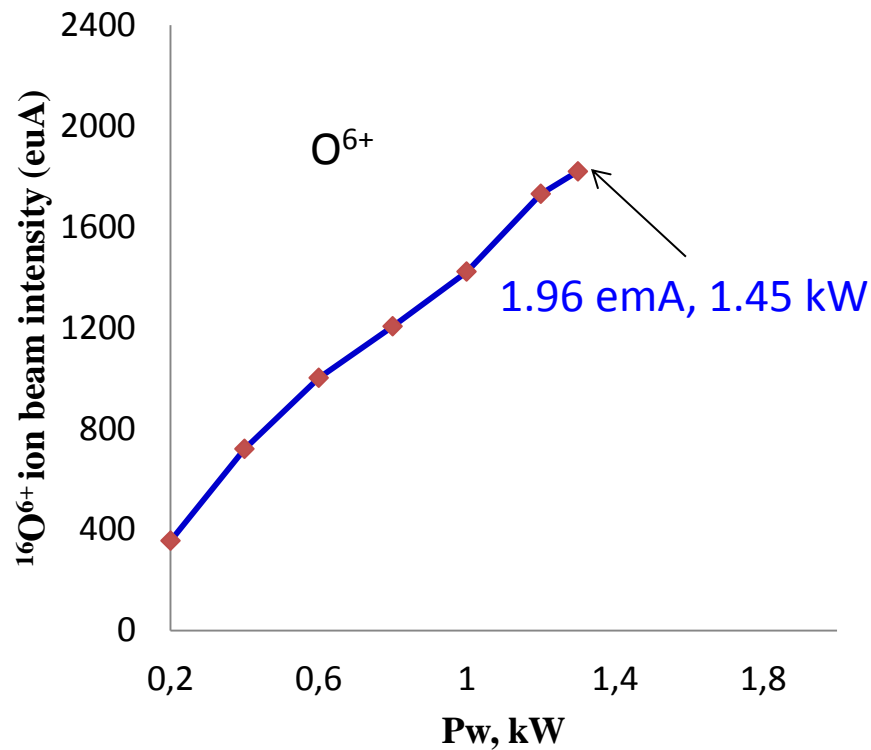
118 eμA  $\text{Bi}^{28+}$ , 89 eμA  $\text{Bi}^{29+}$ , 78 eμA  $\text{Bi}^{30+}$ ,

70.5 eμA  $\text{Bi}^{31+}$ , 23 eμA  $\text{Bi}^{34+}$





# Beam Intensity Evolution vs. RF Power



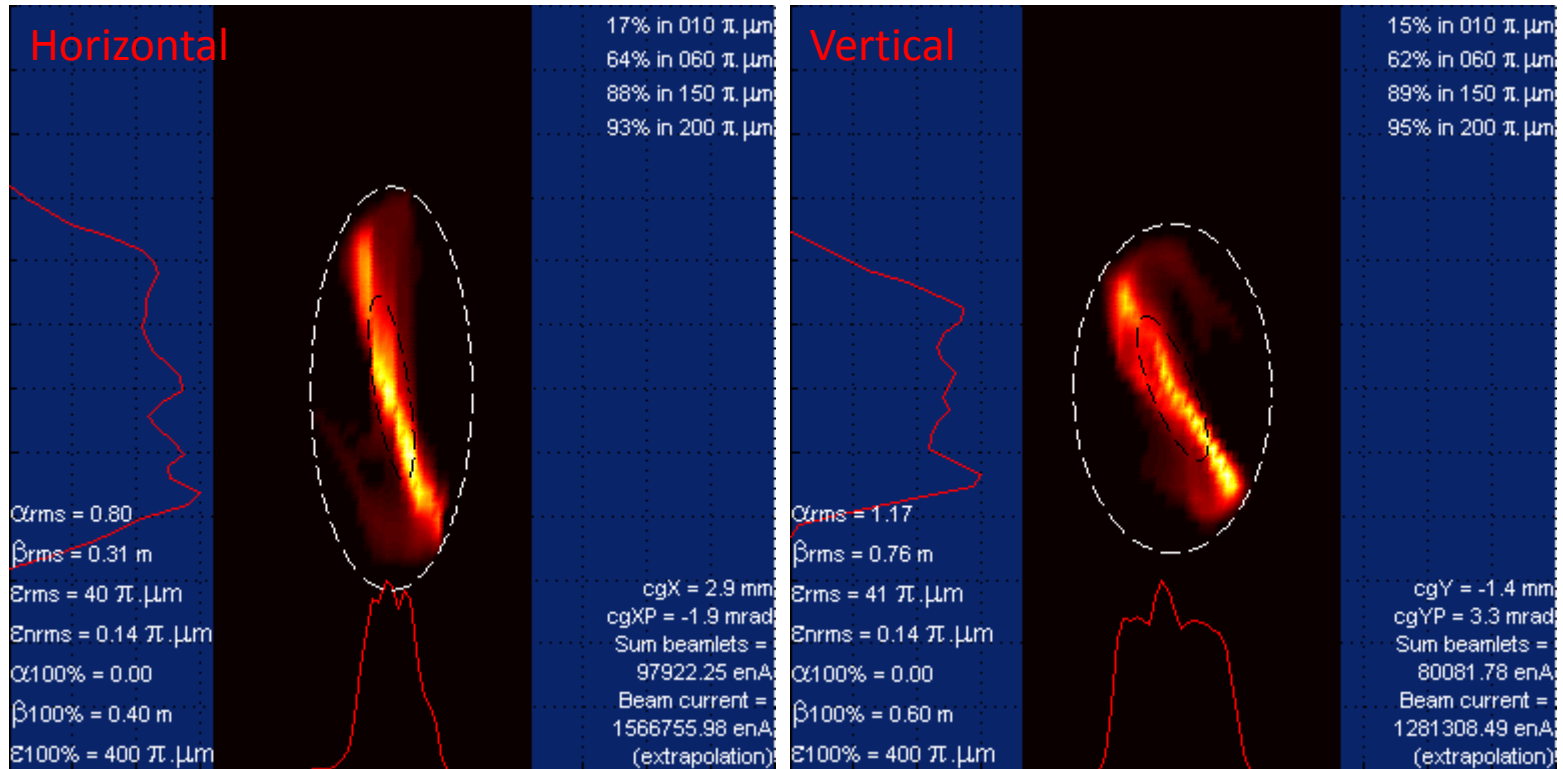
➤ Ion beam intensities are not saturated

➤ To input more power, long tuning time is needed.



# Intense Ion Beam Emittance- Argon

$HV=25\text{ kV}$ ,  $I_o=8.04\text{ emA}$ ,  $Ar^{9+}=1.07\text{ emA}$



88% in 150  $\pi\text{.mm.mrad}$

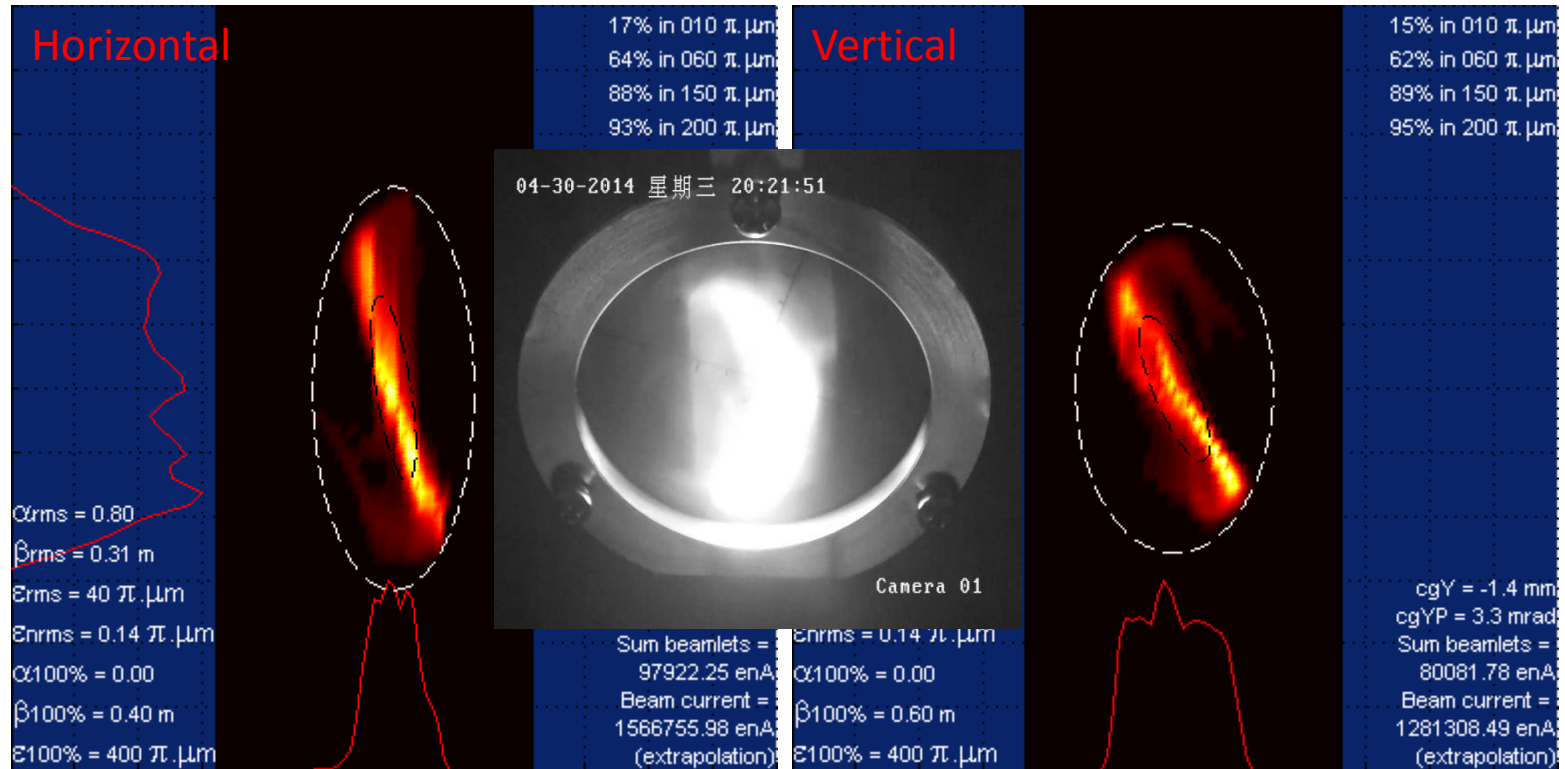
89% in 150  $\pi\text{.mm.mrad}$





# Intense Ion Beam Emittance- Argon

$HV=25\text{ kV}$ ,  $I_o=8.04\text{ emA}$ ,  $Ar^{9+}=1.07\text{ emA}$



88% in  $150\pi\text{ mm.mrad}$

89% in  $150\pi\text{ mm.mrad}$



# Commissioning with RFQ

**Ion species:  $O^{5+}$ ,  $Ar^{8+}$**

**Intensity:  $\sim 200$  euA**

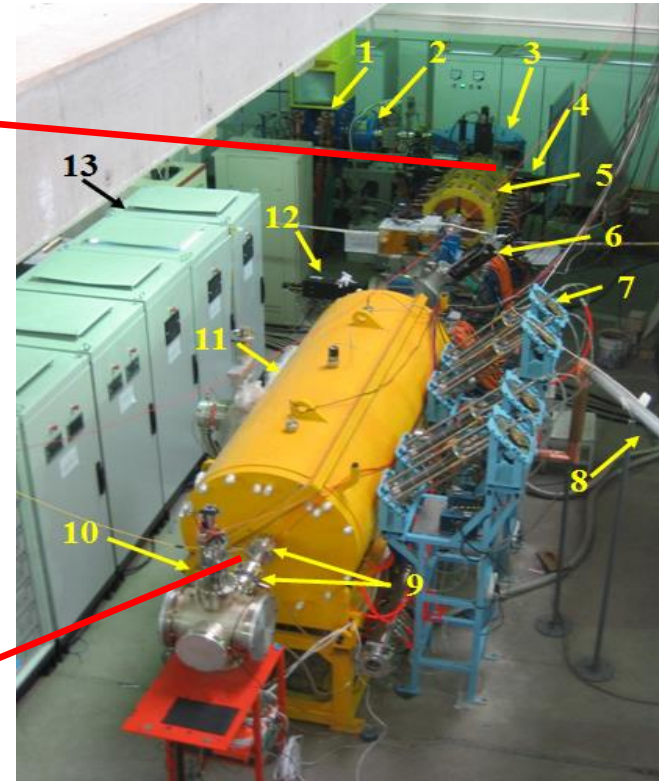
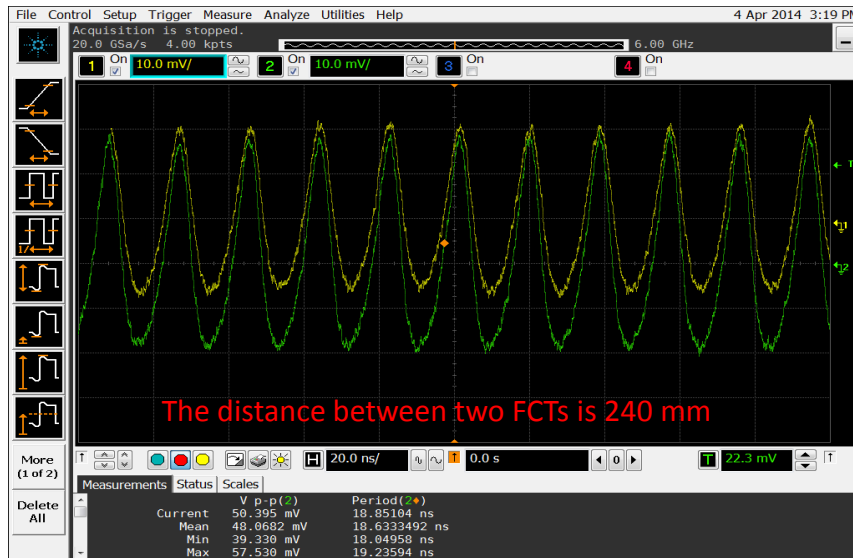
**Extraction HV: 11.92 kV, 18.6 kV**

**$P_w < 200$  W (Only one generator needed)**

**Normalized rms emittance:**

**$\epsilon_x = 0.07 \pi \cdot \text{mm} \cdot \text{mrad}$  ( $Ar^{8+}$ )**

**$\epsilon_y = 0.13 \pi \cdot \text{mm} \cdot \text{mrad}$  ( $Ar^{8+}$ )**



**Final Energy=143 keV/u**

**Transmit Efficiency of**

**RFQ > 90%**

**In about one week's commissioning, the heavy ion beams delivered from LECR4 have been accelerated to the design energy successfully!**

1: ion source, 3: bending magnet, 5: double doublet, 11: RFQ, 9: two FCTs



# Latest Performance of LECR4



|                   |                 | SECRAL <sup>1</sup> | GTS <sup>2</sup> | LECR3 <sup>3</sup> | LECR4         |
|-------------------|-----------------|---------------------|------------------|--------------------|---------------|
| $f$ (GHz)         |                 | 18<br><3.2 kW       | 18<br>>2 kW      | 14<br>&18          | 18<br><1.6 kW |
| <sup>16</sup> O   | 6 <sup>+</sup>  | 2300                | 1950             | 780                | 1970          |
|                   | 7 <sup>+</sup>  | 810                 |                  | 235                | 438           |
| <sup>40</sup> Ar  | 8 <sup>+</sup>  |                     | 1100             | 1100               | 1717          |
|                   | 9 <sup>+</sup>  | 1100                | 920              | 720                | 1075          |
| <sup>129</sup> Xe | 11 <sup>+</sup> | 810                 | 510              | 325                | 503           |
|                   | 20 <sup>+</sup> | 505                 | 310              | 160                | 293           |
|                   | 23 <sup>+</sup> |                     |                  | 130                | 143           |
| <sup>209</sup> Bi | 28 <sup>+</sup> | 214                 |                  |                    | 118           |
|                   | 30 <sup>+</sup> | 191                 |                  |                    | 78            |
|                   | 32 <sup>+</sup> |                     |                  |                    | 51.5          |

1, H.W. Zhao *et al*, RSI, 79, 02A315 (2008).

2, D. Hitz *et al*, RSI, 75, 1403 (2004).

3, Z. M. Zhang *et al*, AIP Conf. Proc. 749, 238 (2005)



# Latest Performance of LECR4



|                   |                 | SECRAL <sup>1</sup> | GTS <sup>2</sup> | LECR3 <sup>3</sup> | LECR4         |
|-------------------|-----------------|---------------------|------------------|--------------------|---------------|
| $f$ (GHz)         |                 | 18<br><3.2 kW       | 18<br>>2 kW      | 14<br>&18          | 18<br><1.6 kW |
| <sup>16</sup> O   | 6 <sup>+</sup>  | 2300                | 1950             | 780                | 1970          |
|                   | 7 <sup>+</sup>  | 810                 |                  | 235                | 438           |
| <sup>40</sup> Ar  | 8 <sup>+</sup>  |                     | 1100             | 1100               | 1717          |
|                   | 9 <sup>+</sup>  | 1100                | 920              | 720                | 1075          |
|                   | 11 <sup>+</sup> | 810                 | 510              | 325                | 503           |
| <sup>129</sup> Xe | 20 <sup>+</sup> | 505                 | 310              | 160                | 293           |
|                   | 23 <sup>+</sup> |                     |                  | 130                | 143           |
| <sup>209</sup> Bi | 28 <sup>+</sup> | 214                 |                  |                    | 118           |
|                   | 30 <sup>+</sup> | 191                 |                  |                    | 78            |
|                   | 32 <sup>+</sup> |                     |                  |                    | 51.5          |

1, H.W. Zhao *et al*, RSI, 79, 02A315 (2008).

2, D. Hitz *et al*, RSI, 75, 1403 (2004).

3, Z. M. Zhang *et al*, AIP Conf. Proc. 749, 238 (2005) W. Lu- ECRIS 2014, Nizhny Novgorod, Russian, 24/28 August 2014, 30



# Latest Performance of LECR4



|                   |                 | SECRAL <sup>1</sup> | GTS <sup>2</sup> | LECR3 <sup>3</sup> | LECR4         |
|-------------------|-----------------|---------------------|------------------|--------------------|---------------|
| $f$ (GHz)         |                 | 18<br><3.2 kW       | 18<br>>2 kW      | 14<br>&18          | 18<br><1.6 kW |
| <sup>16</sup> O   | 6 <sup>+</sup>  | 2300                | 1950             | 780                | 1970          |
|                   | 7 <sup>+</sup>  | 810                 |                  | 235                | 438           |
| <sup>40</sup> Ar  | 8 <sup>+</sup>  |                     | 1100             | 1100               | 1717          |
|                   | 9 <sup>+</sup>  | 1100                | 920              | 720                | 1075          |
|                   | 11 <sup>+</sup> | 810                 | 510              | 325                | 503           |
| <sup>129</sup> Xe | 20 <sup>+</sup> | 505                 | 310              | 160                | 293           |
|                   | 23 <sup>+</sup> |                     |                  | 130                | 143           |
| <sup>209</sup> Bi | 28 <sup>+</sup> | 214                 |                  |                    | 118           |
|                   | 30 <sup>+</sup> | 191                 |                  |                    | 78            |
|                   | 32 <sup>+</sup> |                     |                  |                    | 51.5          |

Room temperature ECRISs

1, H.W. Zhao *et al*, RSI, 79, 02A315 (2008).

2, D. Hitz *et al*, RSI, 75, 1403 (2004).

3, Z. M. Zhang *et al*, AIP Conf. Proc. 749, 238 (2005)



# Summary







# Summary



- ✓ **The first room temperature ECR ion source using evaporative cooling technology--LECR4 has been developed successfully**
- ✓ The performance of LECR4 is promising:
  - Design without injection pump tested working fine
  - High beam intensity
  - Reasonable beam quality
- ✓ Successful RFQ commissioning with stable  $O^{5+}$  &  $Ar^{8+}$  ion beams from LECR4.
- ✓ Total operation time of LECR4 > 1000 Hours



# Acknowledgement

- Thanks the following colleagues from IEE,CAS for their nice work on building a nice magnet:  
**Lin Ruan, Bin Xiong, Shuqing Guo,...**
- Many thanks go to the following colleagues for their kind help and fruitful discussions during design and commissioning of LECR4:  
**Dan.Xie, Peter Spaedtke,...**
- Thanks for your attention!